

EAST Search History

Ref #	Hits	Search Query	DBs	Default Operator	Plurals	Time Stamp
L1	13	sensor\$1.clm. and control\$10.clm. and beam\$2.clm. and optical.clm. and (micro\$1electromechanical.clm or mems.clm. or micromirror\$2.clm.) and (photodiode\$2.clm. or photosensiti\$9.clm. or photodetector\$1.clm. or phototransistor\$1.clm.)	USPAT	OR	OFF	2006/06/02 17:22
L3	13	sensor\$1.clm. and control\$10.clm. and beam\$2.clm. and optical.clm. and (micro\$1electromechanical.clm or mems.clm. or micromirror\$2.clm.) and (photodiode\$2.clm. or photosensiti\$9.clm. or photodetector\$1.clm. or phototransistor\$1.clm.)	US-PGPUB	OR	OFF	2006/06/02 17:24
L4	125	control\$10.clm. and beam\$2.clm. and optical.clm. and (micro\$1electromechanical.clm or mems.clm. or micromirror\$2.clm.) and (photodiode\$2.clm. or photosensiti\$9.clm. or photodetector\$1.clm. or phototransistor\$1.clm. or sensor\$1.clm.)	US-PGPUB	OR	OFF	2006/06/02 17:24
L5	58	control\$10.clm. and beam\$2.clm. and optical.clm. and (micro\$1electromechanical.clm or mems.clm. or micromirror\$2.clm.) and (photodiode\$2.clm. or photosensiti\$9.clm. or photodetector\$1.clm. or phototransistor\$1.clm. or sensor\$1.clm.)	USPAT	OR	OFF	2006/06/02 17:24
L6	38	control\$10.clm. and beam\$2.clm. and optical.clm. and (micro\$1electromechanical.clm or mems.clm. or micromirror\$2.clm.) and (photodiode\$2.clm. or photosensiti\$9.clm. or photodetector\$1.clm. or phototransistor\$1.clm. or sensor\$1.clm.) and control.clm. and beam.clm.	USPAT	OR	OFF	2006/06/02 17:24
L7	96	control\$10.clm. and beam\$2.clm. and optical.clm. and (micro\$1electromechanical.clm or mems.clm. or micromirror\$2.clm.) and (photodiode\$2.clm. or photosensiti\$9.clm. or photodetector\$1.clm. or phototransistor\$1.clm. or sensor\$1.clm.) and control.clm. and beam.clm.	US-PGPUB	OR	OFF	2006/06/02 17:24
L8	85	control\$10.clm. and beam\$2.clm. and optical.clm. and (micro\$1electromechanical.clm or mems.clm. or micromirror\$2.clm.) and (sensor\$1.clm.) and control.clm. and beam.clm.	US-PGPUB	OR	OFF	2006/06/02 17:25
L9	30	control\$10.clm. and beam\$2.clm. and optical.clm. and (micro\$1electromechanical.clm or mems.clm. or micromirror\$2.clm.) and (sensor\$1.clm.) and control.clm. and beam.clm.	USPAT	OR	OFF	2006/06/02 17:26

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L10	0	control\$10.clm. and beam\$2.clm. and optical.clm. and (micro\$1electromechanical.clm or mems.clm. or micromirror\$2.clm.) and sensor\$1.clm. and voltage.clm. and controller.clm. and power.clm. and lead.clm.	USPAT	OR	OFF	2006/06/02 17:26
L11	1	control\$10.clm. and beam\$2.clm. and optical.clm. and (micro\$1electromechanical.clm or mems.clm. or micromirror\$2.clm.) and sensor\$1.clm. and voltage.clm. and controller.clm. and power.clm. and lead.clm.	US-PGPUB	OR	OFF	2006/06/02 17:26
L12	1	control\$10.clm. and beam\$2.clm. and optical.clm. and (micro\$1electromechanical.clm or mems.clm. or micromirror\$2.clm.) and sensor\$1.clm. and voltage.clm. and controller.clm. and power.clm. and lead.clm.	US-PGPUB	OR	OFF	2006/06/02 17:27
L13	0	control\$10.clm. and beam\$2.clm. and optical.clm. and (micro\$1electromechanical.clm or mems.clm. or micromirror\$2.clm.) and sensor\$1.clm. and voltage.clm. and controller.clm. and power.clm. and lead.clm.	USPAT	OR	OFF	2006/06/02 17:27

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Ref #	Hits	Search Query	DBs	Default Operator	Plurals	Time Stamp
S4	8	"359"/ \$.ccls. and (MEMS or microelectromechanical) or (optical near sensor) and (mirror same rotat\$5) and (voltage near controller\$1)	USPAT	OR	OFF	2006/05/23 16:27
S5	3	"359"/ \$.ccls. and (MEMS or microelectromechanical) and (optical near sensor) and (mirror same rotat\$5) and (voltage near controller\$1)	USPAT	OR	OFF	2006/05/29 18:12
S6	34	(MEMS or microelectromechanical) and (optical near2 sensor) and (mirror same rotat\$5)	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	OFF	2003/03/19 09:33
S7	1	(MEMS or microelectromechanical) and (optical near sensor) and (mirror same rotat\$5) and (voltage near controller\$1)	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	OFF	2003/03/19 09:30
S8	9	(MEMS or microelectromechanical) and (voltage near2 sensor) and (mirror same rotat\$5)	US-PGPUB; USPAT; EPO; JPO; DERWENT; IBM_TDB	OR	OFF	2003/03/19 09:57
S9	0	"359"/\$.ccls. and (MEMS or microelectromechanical) and (optical near sensor) and (mirror same rotat\$5) and (voltage near controller\$1)	USPAT	OR	OFF	2003/03/19 10:09
S10	0	"359"/\$.ccls. and (MEMS or microelectromechanical) and (optical near sensor) and (mirror same rotat\$5) and (voltage near controller\$1)	USPAT	OR	OFF	2003/03/19 10:10
S11	55	bruns.in. and donald	US-PGPUB; USPAT	OR	OFF	2006/05/23 16:08
S13	11	S11 and mirror\$1 and sensor\$1	US-PGPUB; USPAT	OR	OFF	2006/05/23 16:09
S14	5	"359"/\$.ccls. and (MEMS or microelectromechanical) and sensor and (voltage near controller\$1)	USPAT	OR	OFF	2006/05/23 16:29
S15	33	"359"/\$.ccls. and (MEMS or microelectromechanical) and sensor and (controller\$1 same sensor\$1)	USPAT	OR	OFF	2006/05/23 18:39
S16	14	"359"/\$.ccls. and (MEMS or microelectromechanical) and sensor and (controller\$1 same sensor\$1) and (control\$5 near8 beam\$1)	USPAT	OR	OFF	2006/05/23 18:39
S17	13856	control\$10 near beam\$2	USPAT	OR	OFF	2006/05/29 23:36
S18	8657	S17 and optical	USPAT	OR	OFF	2006/05/29 18:31
S19	425	S18 and (micro\$1electromechanical or mems or micromirror\$2)	USPAT	OR	OFF	2006/05/29 18:32
S20	258	S19 and (sensor\$1)	USPAT	OR	OFF	2006/05/29 18:33

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S21	119	S19 and (optical near4 sensor\$1)	USPAT	OR	OFF	2006/05/29 18:33
S22	46	S19 and (optical near sensor\$1)	USPAT	OR	OFF	2006/05/29 20:00
S23	1	("5,493,391").PN.	USPAT	OR	OFF	2006/05/29 20:00
S24	1	("5,448,395").PN.	USPAT	OR	OFF	2006/05/29 20:00
S25	277	(control\$10 near beam\$2) and optical and (micro\$1electromechanical or mems or micromirror\$2) and (sensor\$1 or photodiode\$2)	USPAT	OR	OFF	2006/05/29 23:38
S27	231	S25 not S22	USPAT	OR	OFF	2006/05/29 23:37
S28	71	"359"/\$.ccls. and (control\$10 near beam\$2) and optical and (micro\$1electromechanical or mems or micromirror\$2) and (sensor\$1 or photodiode\$2)	USPAT	OR	OFF	2006/05/29 23:47
S29	13	"359"/\$.ccls. and (control\$10 near beam\$2) and optical and (micro\$1electromechanical or mems or micromirror\$2) and (photodiode\$2)	USPAT	OR	OFF	2006/05/30 16:02
S30	8	"359"/290,291,292,293,295,298,299,220, 222,223,224,320,322,323.ccls. and (control\$10 near beam\$2) and optical and (micro\$1electromechanical or mems or micromirror\$2) and (photodiode\$2)	USPAT	OR	OFF	2006/05/30 00:45
S31	610	(control\$10 near beam\$2) and optical and (micro\$1electromechanical or mems or micromirror\$2) and (sensor\$1 or photodiode\$2)	US-PGPUB; USPAT	OR	OFF	2006/05/30 00:44
S32	4	(control\$10 near beam\$2) and optical and (micro\$1electromechanical or mems or micromirror\$2) and (sensor\$1 or photodiode\$2)	EPO; JPO; DERWENT	OR	OFF	2006/05/30 00:45
S33	27	385/16,17,18,19.ccls. and (control\$10 near beam\$2) and optical and (micro\$1electromechanical or mems or micromirror\$2) and (photodiode\$2)	USPAT	OR	OFF	2006/05/30 15:14
S34	0	(controller\$1.ab.) and sensor\$1.ab. and (control\$10 near beam\$2) and optical and (micro\$1electromechanical or mems or micromirror\$2) and (photodiode\$2)	USPAT	OR	OFF	2006/05/30 15:14
S35	5	sensor\$1.ab. and (control\$10 near beam\$2) and optical and (micro\$1electromechanical or mems or micromirror\$2) and (photodiode\$2)	USPAT	OR	OFF	2006/06/02 17:13
S36	16	sensor\$1.bsum. and (control\$10 near beam\$2) and optical and (micro\$1electromechanical or mems or micromirror\$2) and (photodiode\$2)	USPAT	OR	OFF	2006/05/30 15:15
S37	12	"359"/\$.ccls. and (control\$10 near beam\$2) and optical and (micro\$1electromechanical or mems or micromirror\$2) and (photodiode\$2)	US-PGPUB	OR	OFF	2006/05/30 16:22
S38	1	("20030086147").PN.	US-PGPUB	OR	OFF	2006/05/30 16:22